

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



#3  
D.Scott  
5-1002

Applicant: Yamamoto, S., et al.  
Appl. No.: Unknown  
Filed: January 14, 2002  
Title: PRESSURE SENSOR AND MANUFACTURING METHOD THEREOF  
Art Unit: Unknown  
Examiner: Unknown  
Docket No.: 113197-020

Assistant Commissioner for Patents  
Washington, DC 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 37 C.F.R. 1.97, and 37 C.F.R. 1.98, Applicants request that a citation and examination of the references cited below, and on the attached PTO-1449 form, copies of which are enclosed, be made during the course of examination of the above-identified application for United States patent.

U.S. PATENT DOCUMENTS

<u>Document No.</u>	<u>Date</u>	<u>Inventor</u>
3,993,939	November 23, 1976	Slavin et al.
4,092,696	May 30, 1978	Boesen et al.
4,823,230	April 18, 1989	Tiemann
4,831,492	May 16, 1989	Kuisma
4,838,088	June 13, 1989	Murakami
5,186,054	February 16, 1993	Sekimura
5,241,864	September 7, 1993	Addie et al.
5,528,452	June 18, 1996	Ko
5,585,311	December 17, 1996	Ko
5,591,679	January 7, 1997	Jakobsen et al.
5,706,565	January 13, 1998	Sparks et al.
5,929,497	July 27, 1999	Chavan et al.
5,936,164	August 10, 1999	Sparks et al.
6,109,113	August 29, 2000	Chavan et al.

**FOREIGN PATENT DOCUMENTS**

<u>Document No.</u>	<u>Date</u>	<u>Country</u>
11-326095	November 26, 1999	Japan

**OTHER DOCUMENTS**

Seidel, H., et al., "Anisotropic Etching of Crystalline Silicon in Alkaline Solutions," J. Electrochem. Soc., Vol. 137, No. 11, November 1990, pp. 3626-3632.

The cited Japanese patent application is not in the English language. An English abstract is enclosed for the patent application.

Applicants look forward to early and favorable consideration of this matter.

Respectfully submitted,

BELL, BOYD & LLOYD LLC

BY

  
Michael S. Leonard  
Reg. No. 37,557  
P.O. Box 1135  
Chicago, Illinois 60690-1135  
Phone: (312) 807-4270